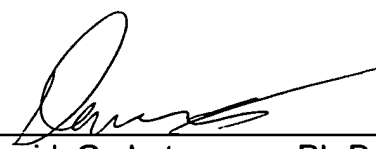


REMARKS

Claims 1-41 are canceled, leaving claims 42-73 pending in the application.
Applicant requests substantive examination of pending claims 42-73.

Respectfully submitted,

Dated: 2/13/02

By: 
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Priority Appl. No. 09/933,913

priority Application Serial No. 09/933,913
priority Filing Date August 20, 2001
Inventor Chen et al.
Assignee Micron Technology, Inc.
priority Group Art Unit 2813
priority Examiner Huynh, Y.
Attorney's Docket No. MI22-1927
Title: Methods of Forming a Capacitor Structure (As Amended)

**VERSION WITH MARKINGS TO SHOW CHANGES MADE
ACCOMPANYING PRELIMINARY AMENDMENT**

In the Specification

The replacement specification paragraphs incorporate the following amendments. Underlines indicate insertions and ~~strikeouts~~ indicate deletions.

The title is amended as follows: ~~Capacitor-Containing Assemblies: and
Methods of Forming Semiconductor Structures~~

Methods of Forming a Capacitor Structure

The following is inserted at Page 1, before the "Technical Field" section,

CROSS REFERENCE TO RELATED APPLICATION

This patent resulted from a divisional application of U.S. Patent
Application Serial No. 09/933,913, which was filed on August 20, 2001.

In the Claims

Claims 1-41 are canceled.

-END OF DOCUMENT-